

PATENT



Attorney Docket No.: A-68359-1 (475852-7)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Gerard S. MOLONEY

Serial No. 10/027,935

Filed: December 21, 2001

For: APPARATUS AND METHOD
FOR CHEMICAL-MECHANICAL
POLISHING (CMP) HEAD
HAVING DIRECT PNEUMATIC
WAFER POLISHING PRESSURE

Group Art Unit: 3724

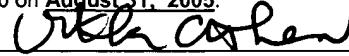
Examiner: ELEY, Timothy V.

Confirmation No.: 2631

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CHANGE OF CORRESPONDENCE ADDRESS

BOX AF

Commissioner for Patents

P. O. Box 1450

Alexandria, Virginia 22313-1450

Please change the correspondence address for the above-identified patent application to the
address indicated below, and address all correspondence to R. Michael Ananian at:

DORSEY & WHITNEY LLP
Intellectual Property Department
555 California Street, Suite 1000
San Francisco, CA 94104-1513

Respectfully submitted,

DORSEY & WHITNEY LLP

By: 

R. Michael Ananian, Reg. No. 35,050

Dated: 8/31/2005

Customer Number: 32940
DORSEY & WHITNEY LLP
Intellectual Property Department
555 California Street, Suite 1000
San Francisco, CA 94104-1513
Telephone: (415) 781-1989
Facsimile: (415) 398-3249